Status of ScECAL At Shinshu



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- two scintillator strip layers for beam test with China-Japan SC-ECAL project

- **Strip uniformity** study with simulation to be compatible with measurements

CALICE Tech. prototype

two layers

- scintillator strip ECAL < Phycs. proto.
- embedded electronic-read out board —
- stacking 32 layers with China & Japan
- Shinshu is preparing two layers

SCECAL technological

electron

beam





calibration by LED & MIP

Bottom readout

- MIP 138/144 (96%)
- LED 130/144 (90%)

Center readout

- MIP 106/144 (74%)
- LED 99/144 (69%)

Need more effort to finish calibrations

 calibration at fixed area due to missing registers





comparison of two layers

- one photon gain(1 p.e.) from LED calib. in ADC unit
- one MIP gain from MIP Calib. in ADC unit
- Light Yield for each strips by p.e. unit for MIP
- bottom readout layer with wedged strip : 13.8 p.e. with 1mmx1mm PPD
- center readout layer with center dimple strip : 43.3 p.e. 1.3mmx1.3mm



cosmic ray test

- set up with combined two layers
- taking data as much as possible with 2Hz
- uniformity by cosmic
- temperature coefficients will be measured





scintillator strip and PPD

- dimple at strip center
- where a PPD is set to collect scintillation lights efficiently
- dip and bump structure
- uniformity along the strip







strip uniformity

- uniformity measurement results show
- polished dimple is NOT good
- than unpolished
- simulation study with rough surface at dimple



LY(p.e.)

30H

20⊢

^a polished

dimple

position vs LY(p.e.)

22

0.7727

24.88

8.469

2.335

22

8.88

Entries

Mean x

Mean y

Std Dev x

Std Dev y

uniform-T0-06nov2020.d

UNIFIED model

- parameters
 - α : surface angle with
 - $0 + \sigma \alpha$: gaussian
 - reflection probability
- normal reflection (C_{sl})
- Lambert reflection (C_{dl})
- mirro scat. (C_{ss})
- back scat. (C_{bs})
- $C_{sl} + C_{dl} + C_{ss} + C_{bs} = 1$



refracted

fully polished strip tuning parameters for fully polished strip

• polished : $\sigma \alpha = 0$ and normal reflection = 1 ? at dimple



roughness at dimple keeping almost smooth surface at other surface





summary and outlook

- two layers of scintillator strips have been almost ready to go to beam test at DESY in 2021
 - LED and MIP calibrations > Bias voltages and threshold are determined as well as other common parameters
 - cosmic ray data taking is on going
- scintillator uniformity is well understood with G4 simulation together with surface treatment
 - better uniformity strip may be produced



look for the best parameter set

